

Electronic Patent Application Fee Transmittal

Application Number:	10821310			
Filing Date:	08-Apr-2004			
Title of Invention:	Apparatus for controlling gas flow in a semiconductor substrate processing chamber			
First Named Inventor:	Kallol Bera			
Filer:	Keith Patrick Taboada			
Attorney Docket Number:	8549/ETCH/DRIE/JB1			
Filed as Large Entity				
Utility Filing Fees				
Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Basic Filing:				
Pages:				
Claims:				
Claims in excess of 20	1202	1	50	50
Miscellaneous-Filing:				
Petition:				
Patent-Appeals-and-Interference:				
Post-Allowance-and-Post-Issuance:				
Extension-of-Time:				

Description	Fee Code	Quantity	Amount	Sub-Total in USD(\$)
Miscellaneous:				
Total in USD (\$)				50